



IRW  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Adrian KIERMASZ

Application No. 10/743,923

Filed: December 22, 2003

For: LINEAR CHEMICAL MECHANICAL  
PLANARIZATION (CMP) SYSTEM AND  
METHOD FOR PLANARIZING A WAFER  
IN A SINGLE CMP MODULE

) Attorney Docket No. LAM2P452

) Examiner: M. Rachuba

) Group Art Unit: 3723

) Confirmation No. 9016

) Date: February 7, 2006

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on February 7, 2006.

Signed: 

Diane Schwanbeck

Commissioner for Patents  
Alexandria, VA 22313-1450

Sir:

Applicant hereby transmits an Amendment in the above-identified application.

The fee has been calculated as shown below.

	Claims Remaining After <u>Amendment</u>	Highest Previously <u>Paid For</u>	Present <u>Extra</u>	<u>SMALL ENTITY</u> <u>RATE FEE</u>	OR	<u>LARGE ENTITY</u> <u>RATE FEE</u>
TOTAL CLAIMS	<u>05</u> -	<u>20</u>	<u>00</u>	X 25 = \$	OR	X 50 = \$0
INDEP CLAIMS	<u>01</u> -	<u>04</u>	<u>00</u>	X100 = \$	OR	X200 = \$0
[ ] Multiple Dependent Claim Present and Fee Not Previously Paid				\$180		\$360
TOTAL				\$ _____		\$0



Applicant hereby petitions for a \_\_\_\_-month extension of time to respond to the Office Action.



Applicant believes that no extension of time is required; however, if it is determined that such an extension is required, Applicant hereby petitions that such an extension be granted and authorize the Commissioner to charge the required fees for an extension of time under 37 CFR 1.136 to Deposit Account No. 50-0805 (Order No. LAM2P452).



Enclosed is our Check No. \_\_\_\_ in the amount of \$ \_\_\_\_ to cover the extension of time fees.



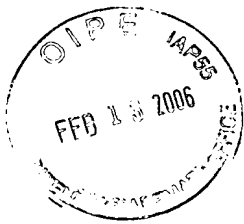
If the required fees are missing or any additional fees are required to facilitate filing the enclosed response, please charge such fees or credit any overpayment to Deposit Account No. 50-0805 (Order No. LAM2P452).

Respectfully submitted,  
MARTINE PENILLA & GENCARELLA, LLP



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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:	)	
Adrian KIERMASZ	)	Docket No. LAM2P452
Application No. 10/743,923	)	Examiner: M. Rachuba
Filed: December 22, 2003	)	Group Art Unit: 3723
For: LINEAR CHEMICAL MECHANICAL	)	Date: February 7, 2006
PLANARIZATION (CMP) SYSTEM	)	Confirmation No. 9016
AND METHOD FOR PLANARIZING A	)	
WAFER IN A SINGLE CMP MODULE	)	

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Signed: \_\_\_\_\_

Diane Schwanbeck

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Applicant submits this paper in response to the Office Action dated November 7, 2005. Please amend this application as follows:

The **Amendments to the Claims** made herein are reflected in the **Listing of Claims**, which begins on page 2 of this paper.

Applicant's **Remarks** begin on page 4 of this paper.